



Micro/Macro Integration of Nanostructures and Nanomaterials

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The Charles Stark Draper Laboratory, Inc.

Innovative Engineering for Over 75 Years

Independent, not-for-profit

Dedicated to

Applied research and development

Technology transfer

Advanced technical education

Divested from MIT in 1973

Headquarters in Cambridge, Mass.

**Site offices in Houston; Huntsville;
Tampa Bay; and Washington, D.C.**

Revenues exceed \$420 million

Approximately 1400 employees

65% technical staff

$\frac{2}{3}$ with advanced degrees



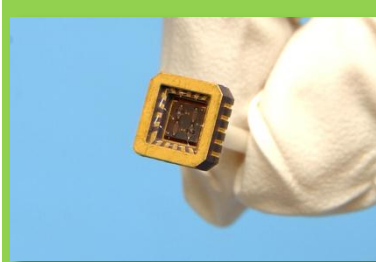
Photo credit: John Earle

Draper's Evolution

From the Birthplace of Inertial Navigation to Advanced Engineering R&D



Guidance, Navigation & Control



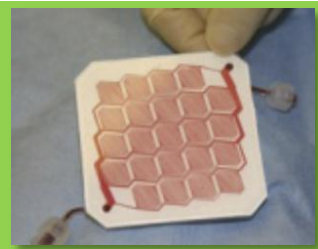
MEMS



Robotics



Fault Tolerance



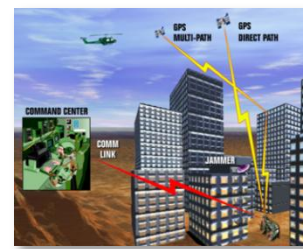
Biomedical Engineering



Microsystems



Autonomous Systems

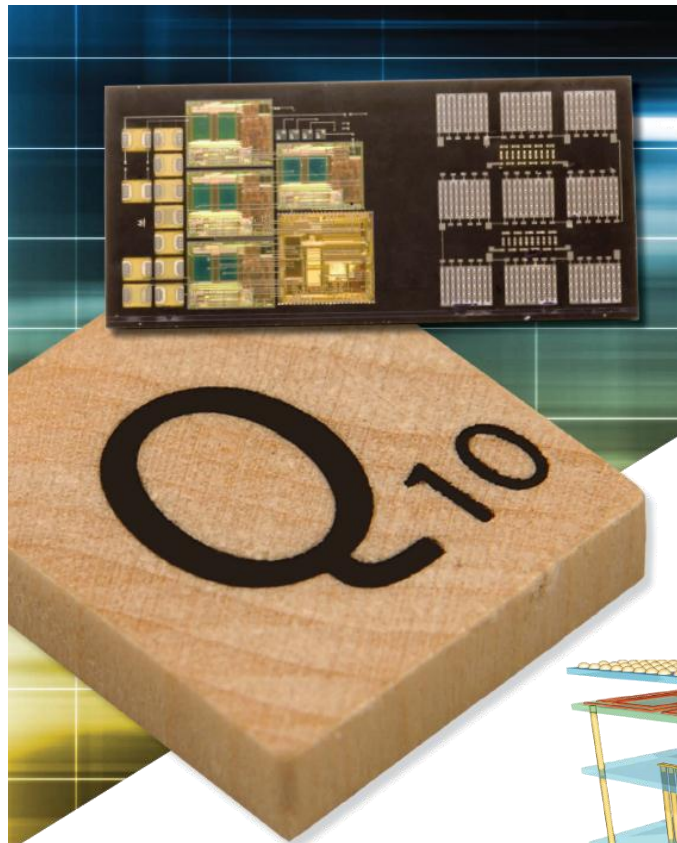


Distributed Communications & Control

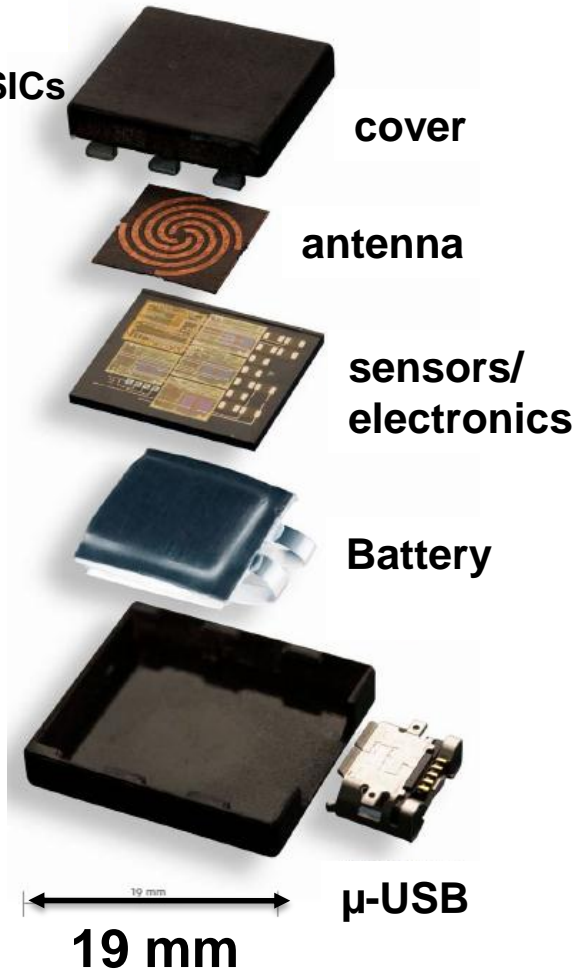
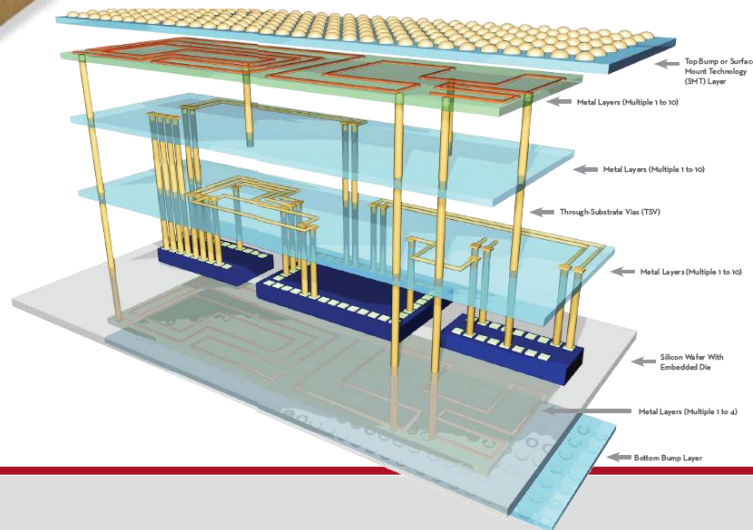


Critical System Design

Vanishingly Small Systems



- Sensors
- DSP in FPGA
- Large Value Passives
- Mixed Signal and Structured ASICs
- Thermal Management
- High Efficiency RF PA
- Algorithms
- i-UHD Electronics Packaging
- Frequency Reference
- RF MEMs
- Antennas
- Power Source
- Waveforms/Protocols



Nanotechnology at Draper

- Mainly in MEMS and Biomedical Areas (some robotics)
- Typically, nanostructured element or nanomaterials integrated with MEMS device or other micro/macro system
- Extensive interactions/collaborations with universities
- Areas:
 - Nanostructured polymers
 - tissue engineering, gecko adhesion
 - Nanostructured metal films
 - chem/bio sensors
 - CNT integration with MEMS
 - Applications: rotary MEMS (e.g. gyroscope, ...)



Nanostructured Polymers



Typical process



Spin coat and
pattern photoresist



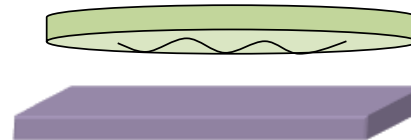
Develop
photoresist



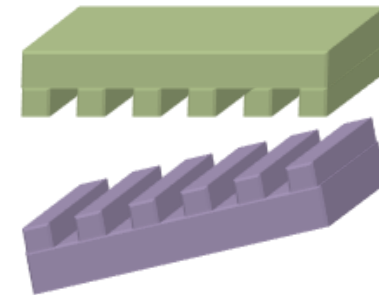
Reactive Ion Etch
Si and/or SiO₂



Strip
photoresist



Pour/emboss
polymer onto mold



Demold

Feature sizes: few microns → ~50 nm

- optical contact litho (~400 nm), e-beam litho, interference litho, diblock copolymers, ...
- *n.b.* shown below are ~800 nm features, but exploring finer topography as well

Molds: Si, SiO₂, electroplated Ni, ...

Wide variety of polymers

Also investigated injection nanomolding with Si inserts

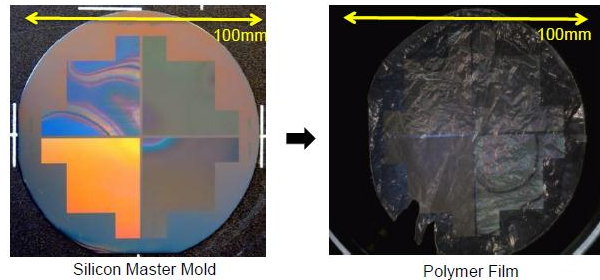
Tissue Engineering

- **Long-term goal:** Micro/nanotopography to cue stem cell growth/behavior for proper function as replacements in existing organs and/or in artificially-engineered organs
 - e.g. **retinal cells** for macular degeneration, retinitis pigmentosa
 - e.g. **renal tubule cells** for kidney disease
- **Current Research:** Create synthetic cellular environments to attempt to replicate native environment of cells
 - Investigate cell type-specific responses, such as alignment, elongation and cell-cell junction formation in a physiologically realistic environment
 - Contribute to research surrounding cellular superstructure formations and stem cell differentiation as well as to the ever-growing fields of tissue engineering and regenerative medicine

Retinal stem cells cultured on polycaprolactone thin film

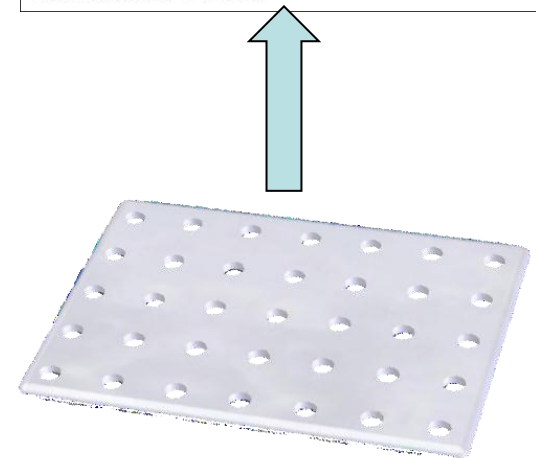
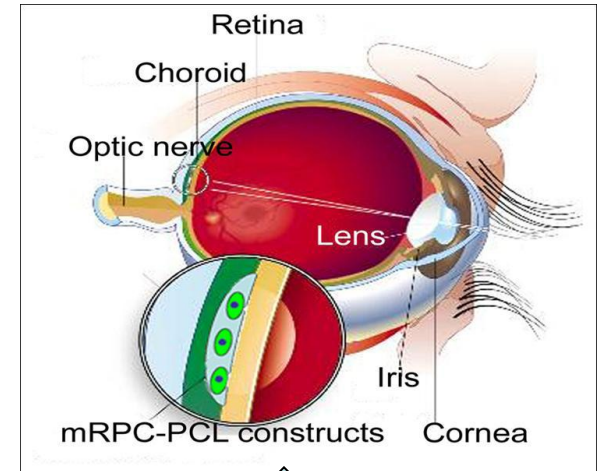
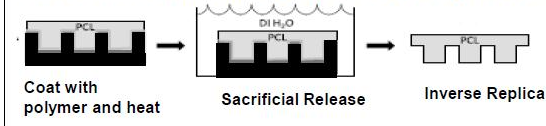
- Thin for subretinal transplantation (<10um)
- Can deliver large population of cells
- Provide cell guidance with submicron cues
- Relatively stiff for surgical manipulation
- Flexible for curvature
- Biocompatible/biodegradable in sub-retinal space

FILM MOLDING PROCESS:

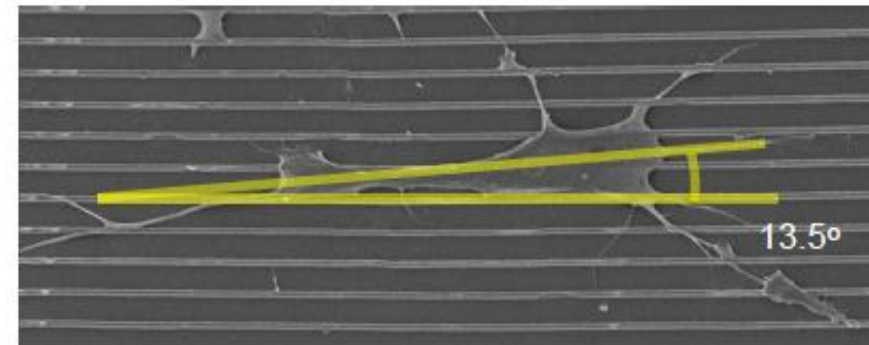
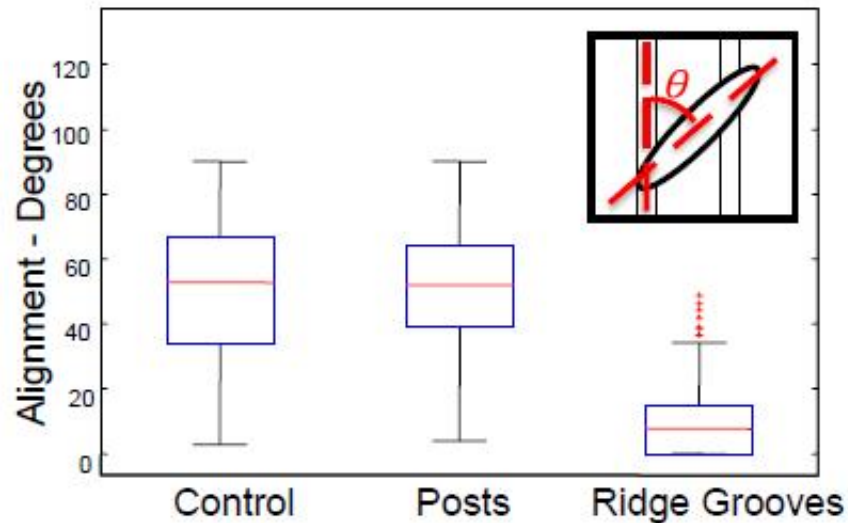
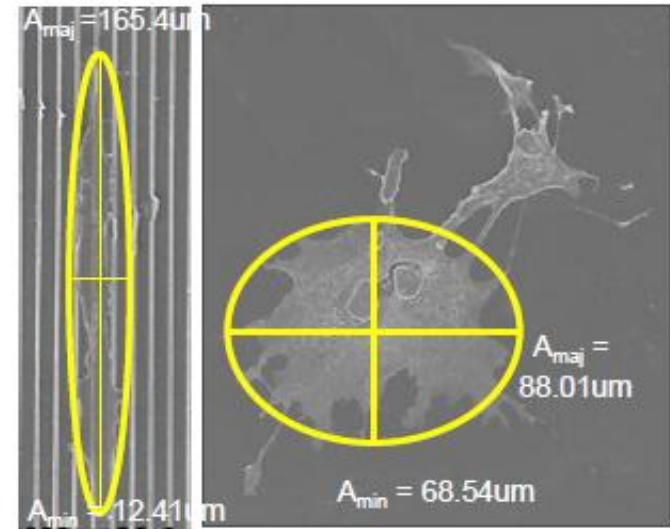
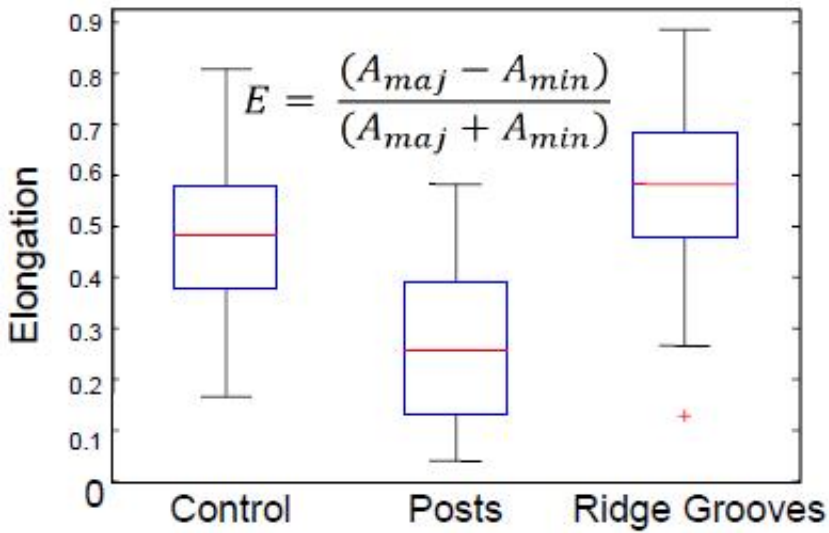


In-vitro Culture

Micromolding/Nanotemplating Polymers



Retinal stem cell morphology response to micro/nano features

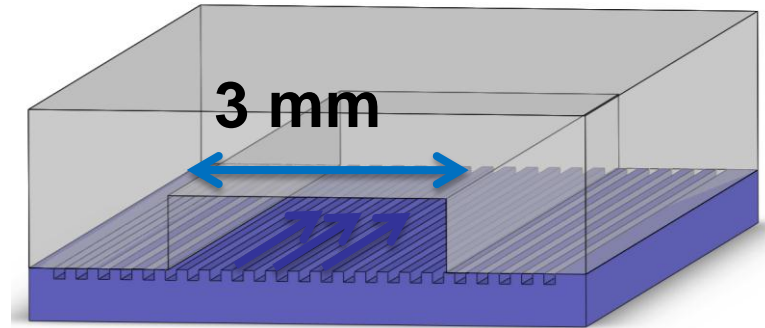
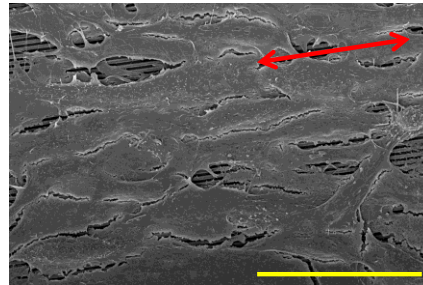
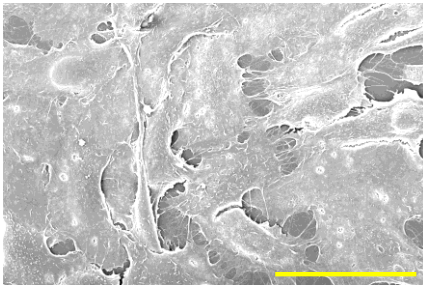
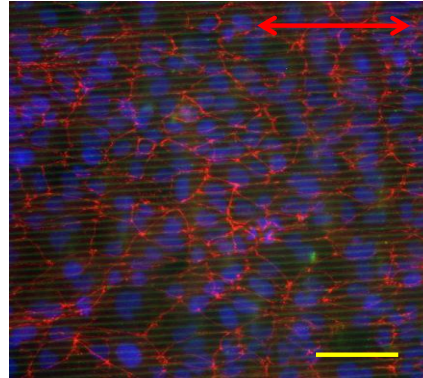
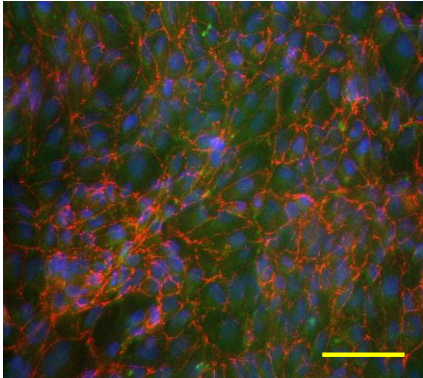


Kidney tubule cell culture

Flat PS

Patterned PS

ZO-1, Megalin, Nuclei

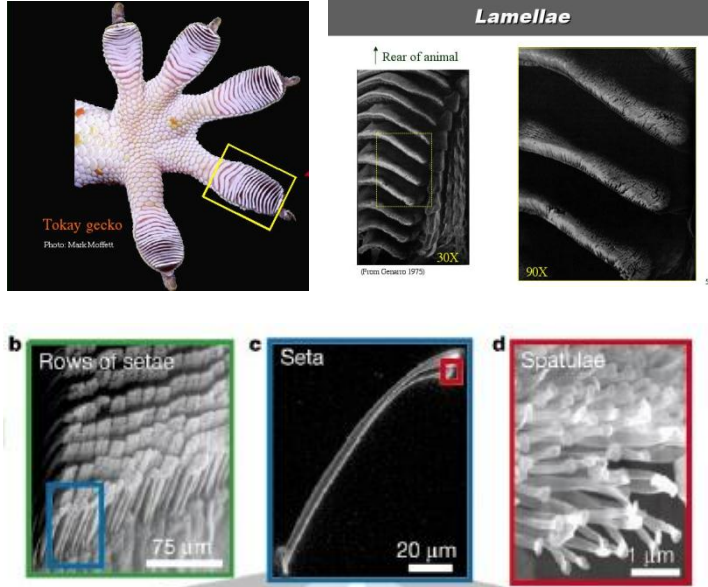


Next step: add microfluidic flow chamber to flow-induced shear stress (FSS) similar to kidney tubule environment

- Human renal proximal tubule cells
- Ridge-groove features horizontal (red arrows)
 - 0.9-1.0 μm in width.
- Cells align and elongate only on the patterned PS
- All scale bars 50 μm

Nanopatterned Artificial Gecko Adhesive

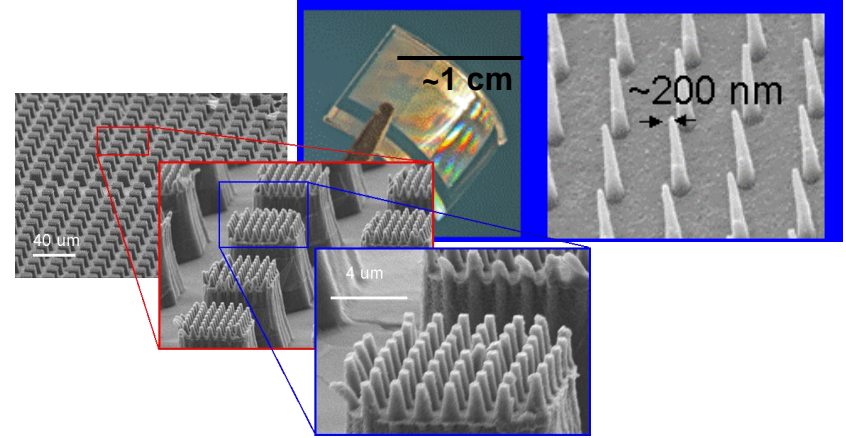
Biomimetic adhesive (one-sided velcro)



<http://www.lclark.edu/~autumn/climbing/>

Artificial gecko adhesive fabrication:

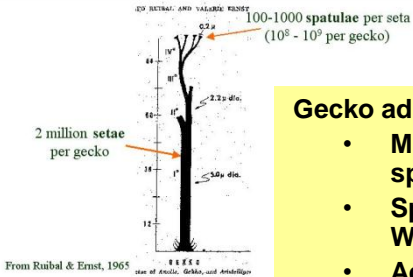
- Use nanolithography to pattern nanomolds
- Mold and release polymers



Biomimetic material adheres better than gecko

Test Surface	Roughness (μm)	Adhesion (mN/mm^2)	
		Normal	Shear
Glass	0	332.4	300.9
Al (polished)	0.7	223.6	56.2
PVC	1.5	11.9	24.7
Al (as received)	1.8	172.6	
Roughened Si	3.25	93.1	6.5
Al (0.120 grit)	8.1	47.6	
Drywall	11.3	7.8	

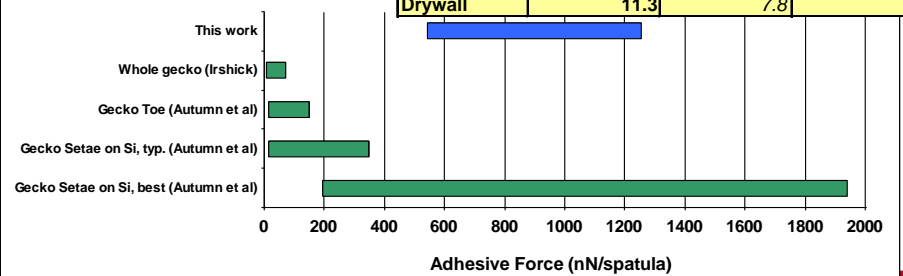
Gecko Seta Structure



Gecko adhesion:

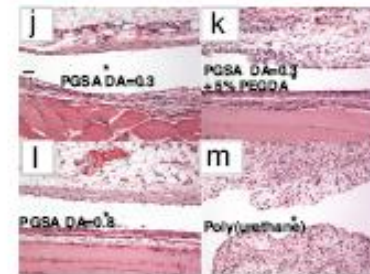
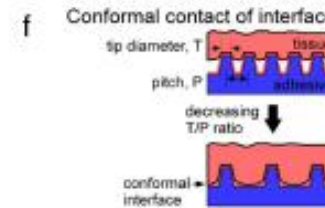
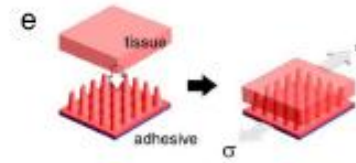
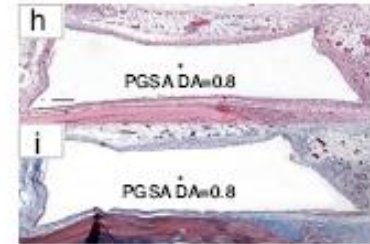
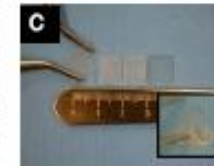
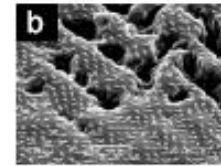
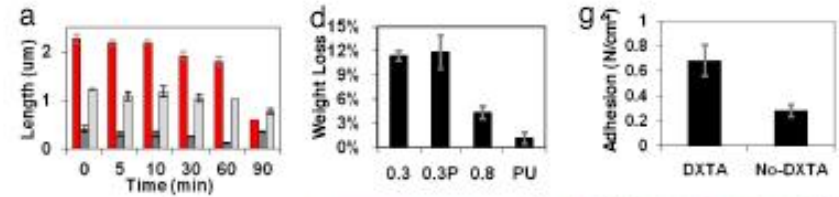
- Millions of tiny (~200 nm) spatulae
- Spatulae adhere by van der Waals forces
- Adheres to a variety of surfaces, wet/dry, etc.

Parallel Adhesive Force Data



Gecko-based Medical Adhesive

- Fabricate micro/nanostructures of biodegradable polymers
- *Functionalize surfaces of structures* to improve adhesion to tissue
- Test adhesion to tissue (porcine intestines)
- Implant into rats and observe inflammation response (~none)



Potential application to wound sealing, augmenting surgical sutures or staples



Biomimetic Adhesion (DARPA Zman)

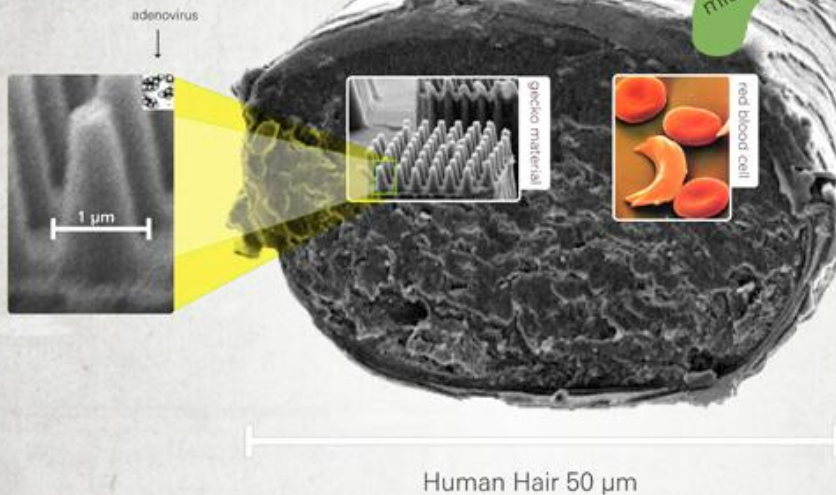
Developing climbing aids to enable an individual soldier to scale vertical walls constructed of typical building materials without ropes or ladders.



The inspiration for these climbing aids is the technique by which geckos, spiders, and small animals scale vertical surfaces, that is, by using unique biological material systems that enable controllable adhesion using van der Waals forces or by hooking surface asperities.



Insect microspine:
Hook into small asperities on surface



Gecko adhesion:
Millions of tiny (~200 nm) spatulae adhere by van der Waals forces. The support structure ensures intimate contact between spatulae and surface.



Approved for Public Release,
Distribution Unlimited





Nanostructured Metal Films



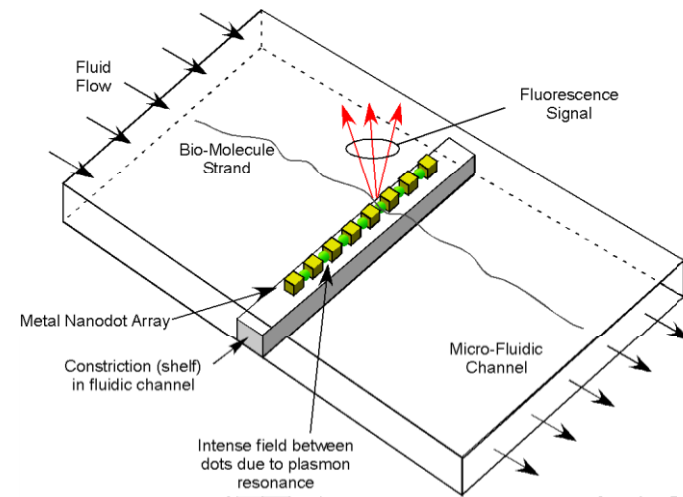
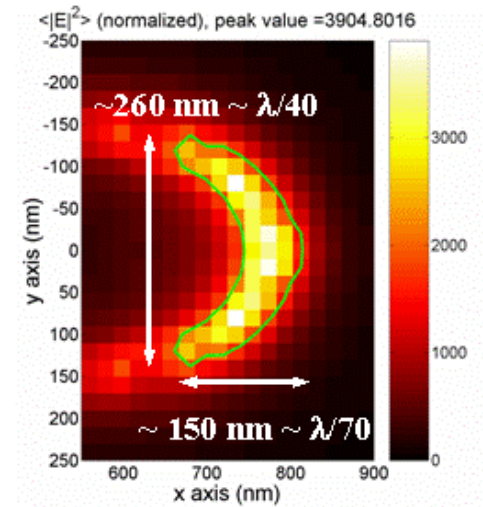
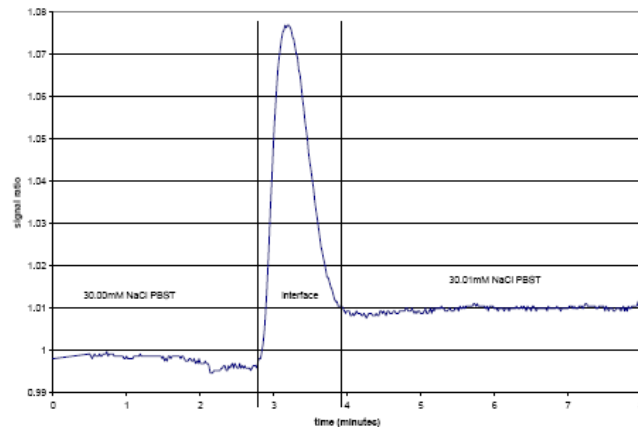
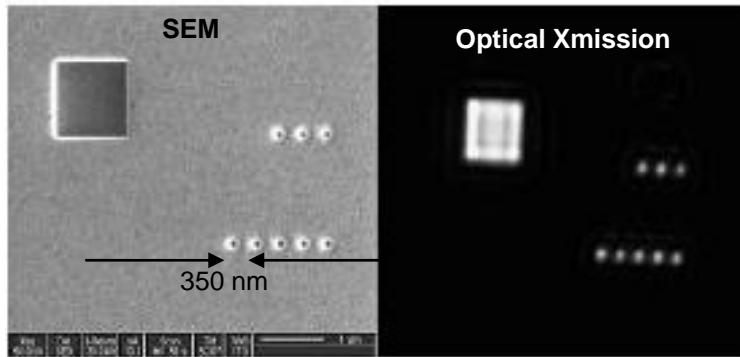
Plasmonics Phenomena and Applications

- **Plasmonic nanoantenna**

- DNA Sensor

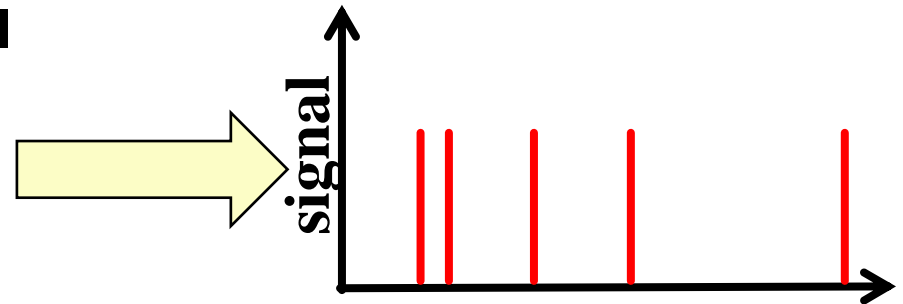
- **Extraordinary Optical Transmission (EOT)**

- Biosensor/Calorimeter

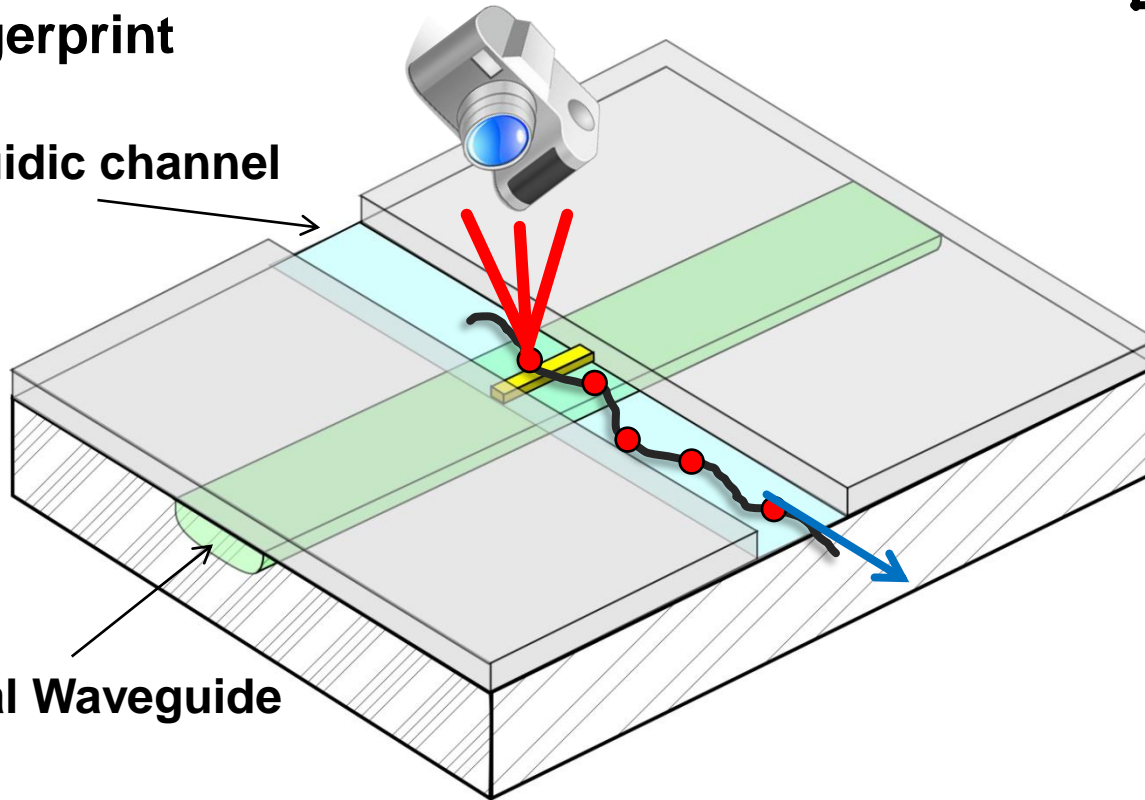


Direct Linear Analysis (DNA detection)

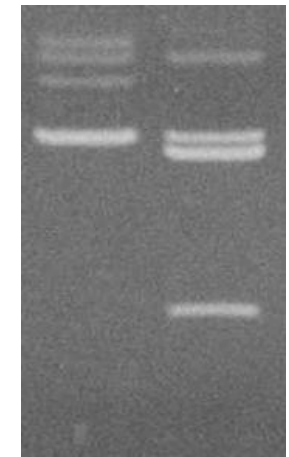
- Tagged DNA flows through channel
- Observe fluorescence with camera
- Spacing produces characteristic fingerprint



Ufluidic channel

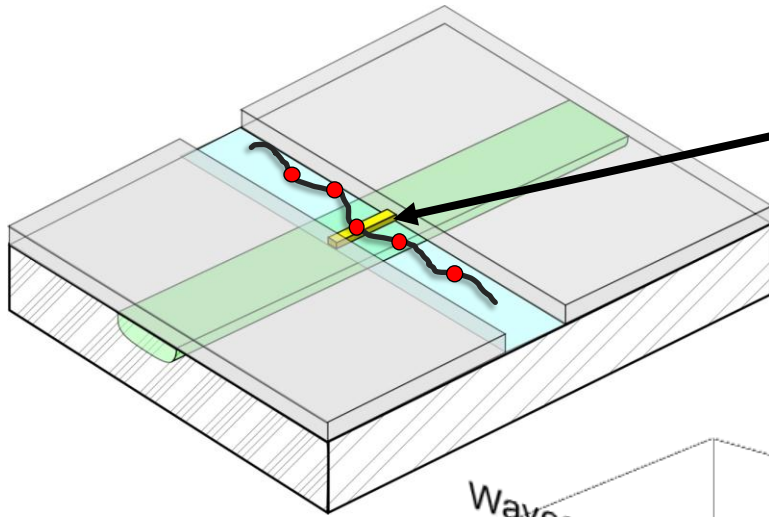


time



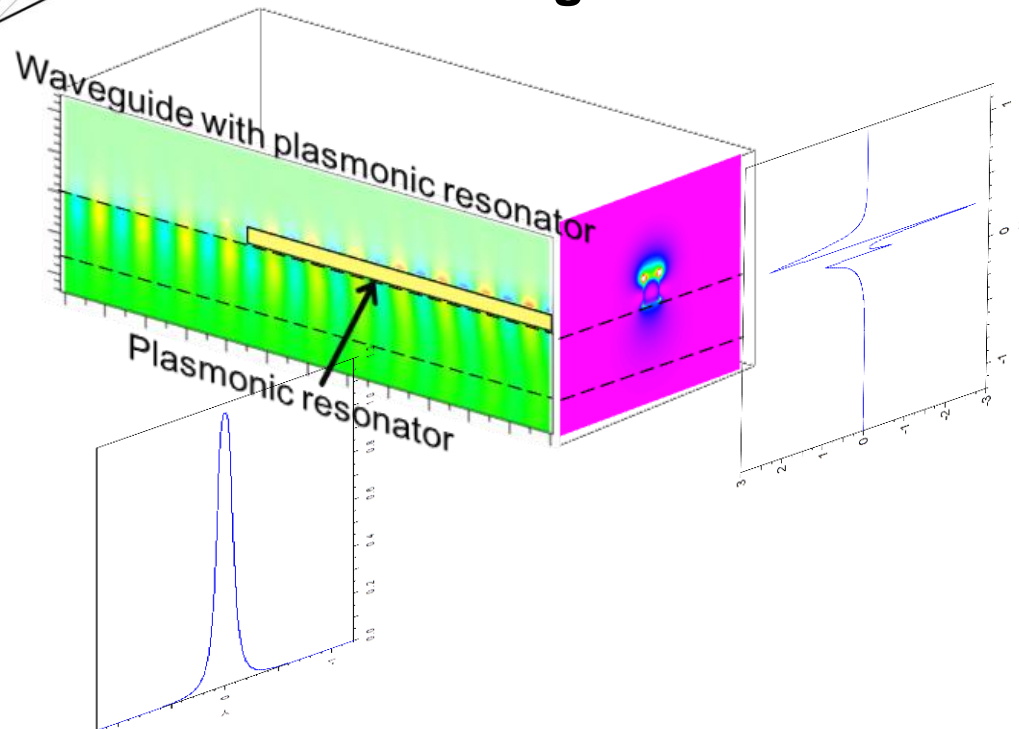
Output analogous to PCR and gel electrophoresis

Single Molecule \rightarrow no PCR

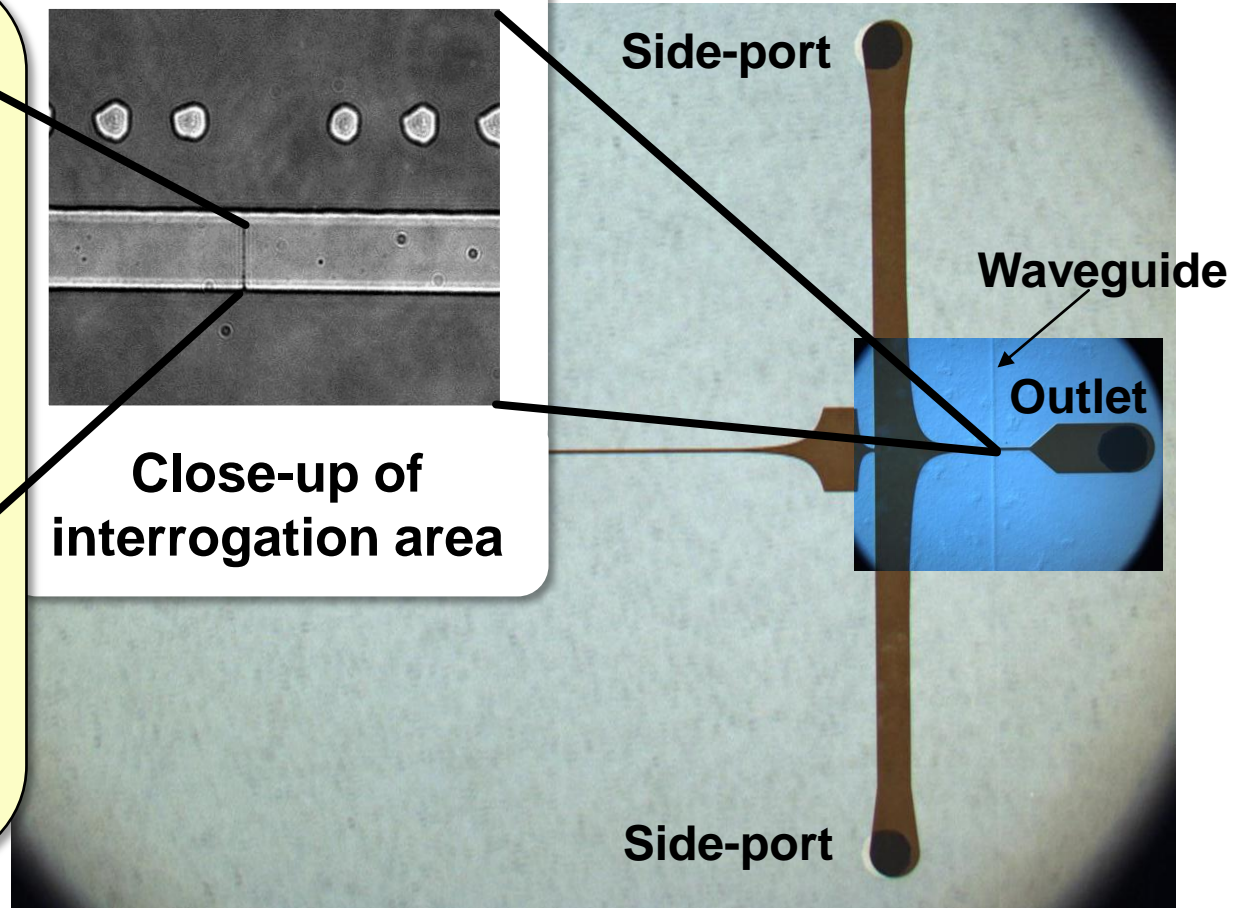
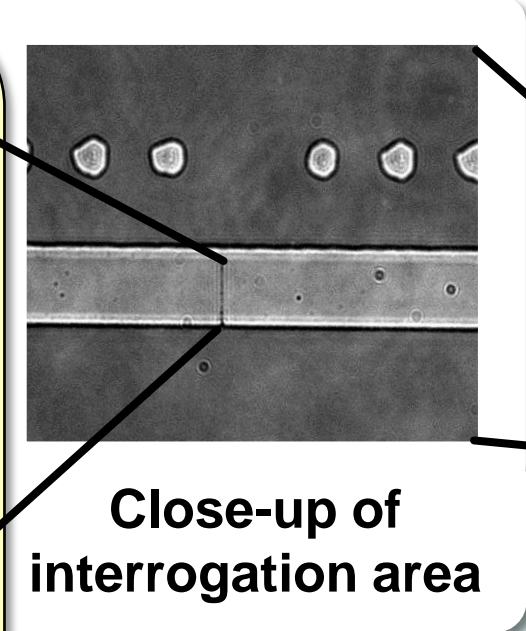
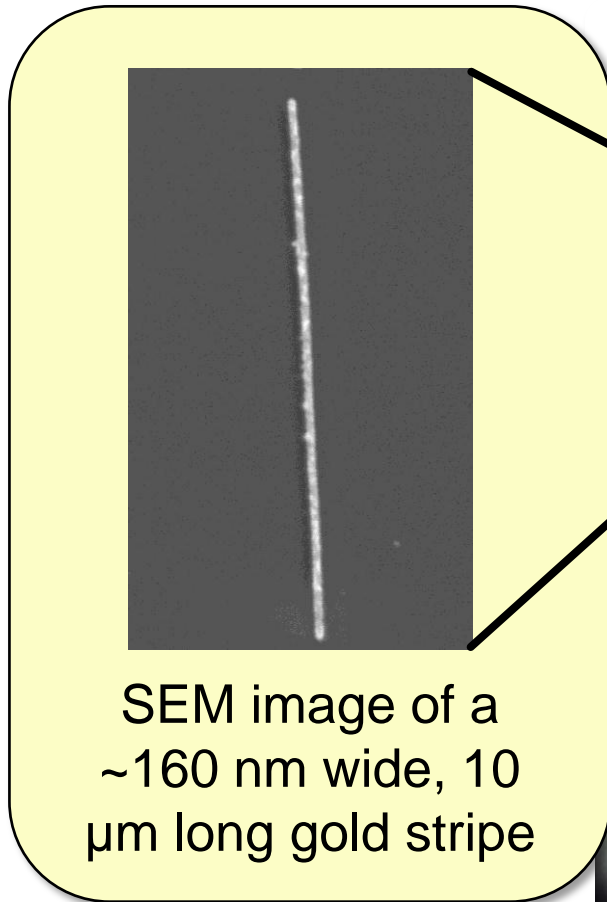


Only want excitation here, no radiation otherwise...

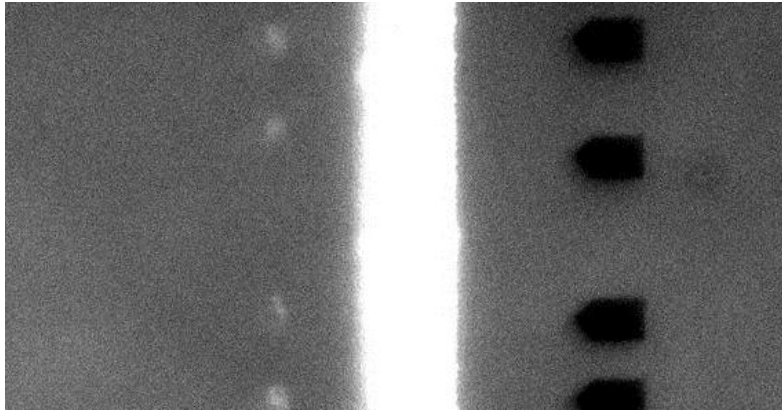
Plasmonic antenna confines light to $\ll \lambda$



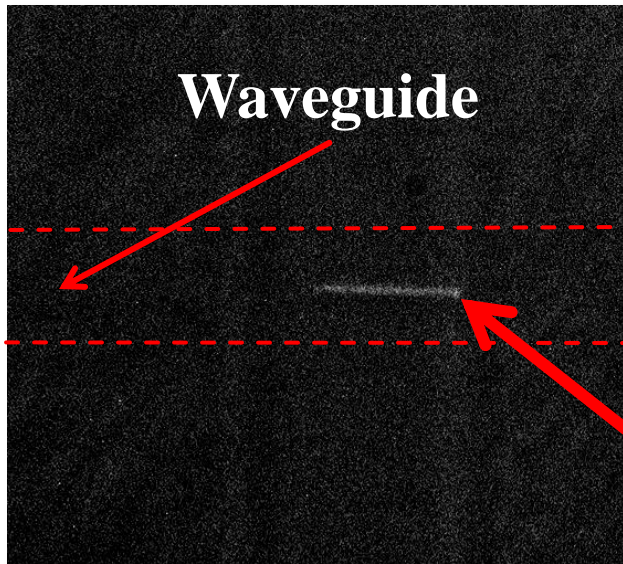
Fabrication



Testing



**Channel filled with dye solution
- Arc lamp illumination**



**Channel filled with dye solution
- Laser input**

Plasmonic resonance exciting fluorophores

Principle of Nanohole Array Biosensing System

Extraordinary Optical Transmission (EOT)

EOT is induced when satisfying:

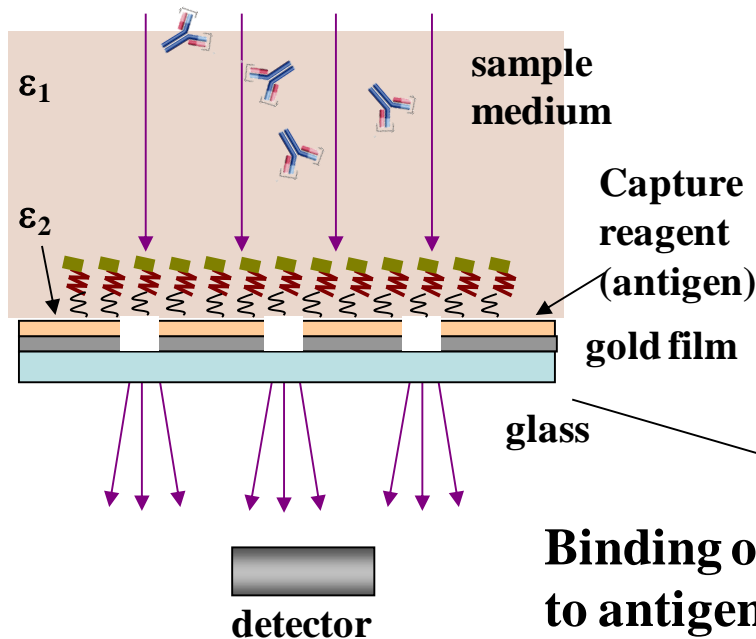
$$\left(\frac{\epsilon_1 \epsilon_2}{\epsilon_1 + \epsilon_2}\right)^{\frac{1}{2}} - \sin \theta = \frac{v\lambda}{a}$$

Δ in ϵ_1 :

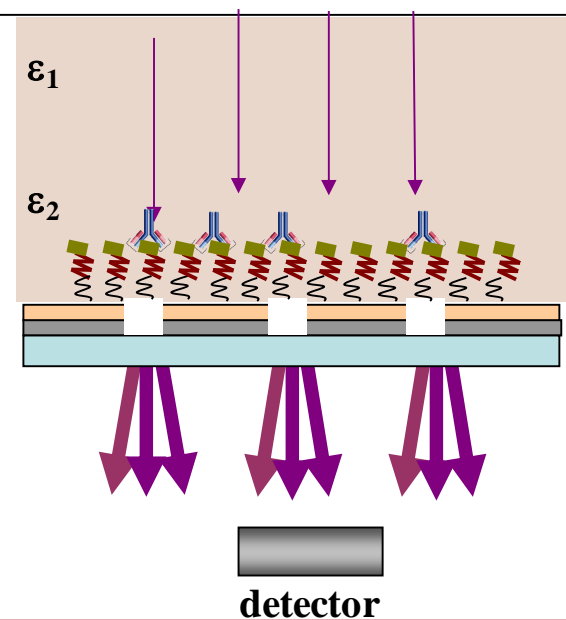
- (1) Temperature
- (2) Changes in the bulk medium

Δ in ϵ_2 :

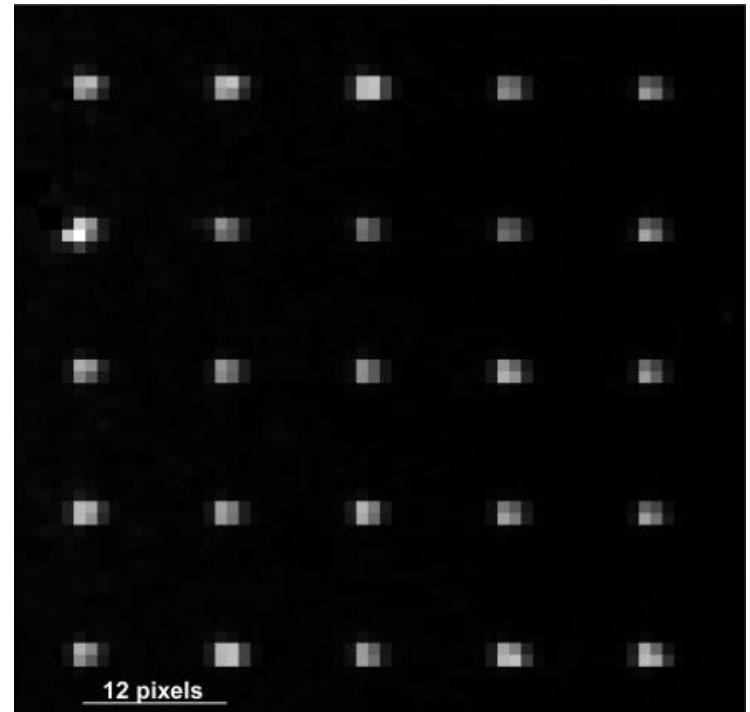
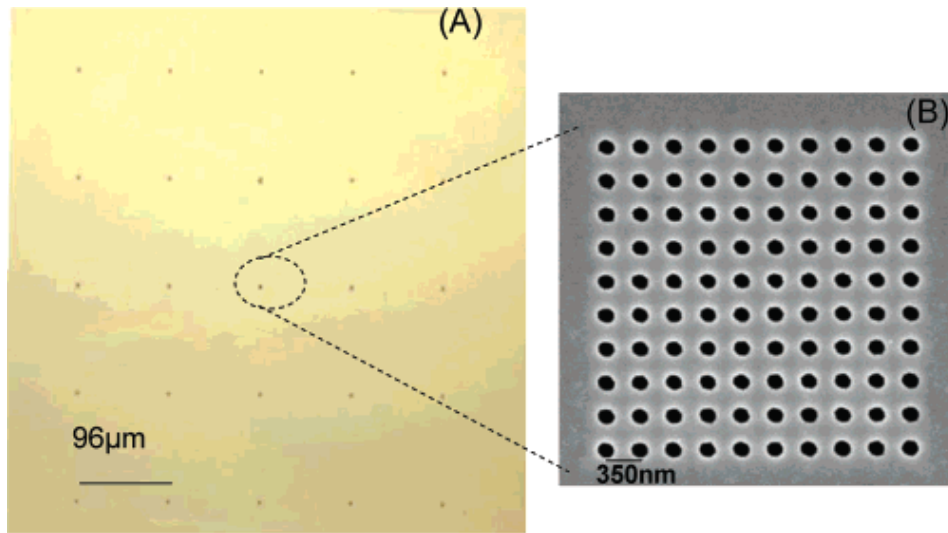
Binding or dissociation events of targets to immobilized capture agents



Binding of antibody to antigen induces $\Delta\epsilon_2$, therefore Δ EOT



Possibly next generation of SPR



Potential Applications:

Binding Assays:

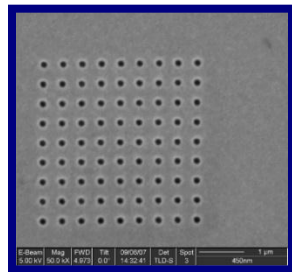
Multiplex detection of cancer biomarkers

Protein array

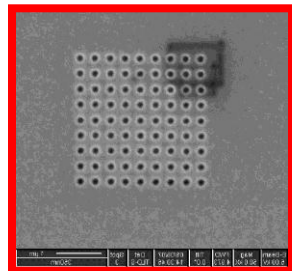
Calorimetry

Multiplexed sensing with nanohole references

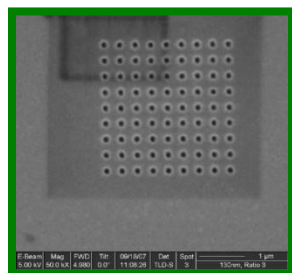
Sensor performance can be tailored



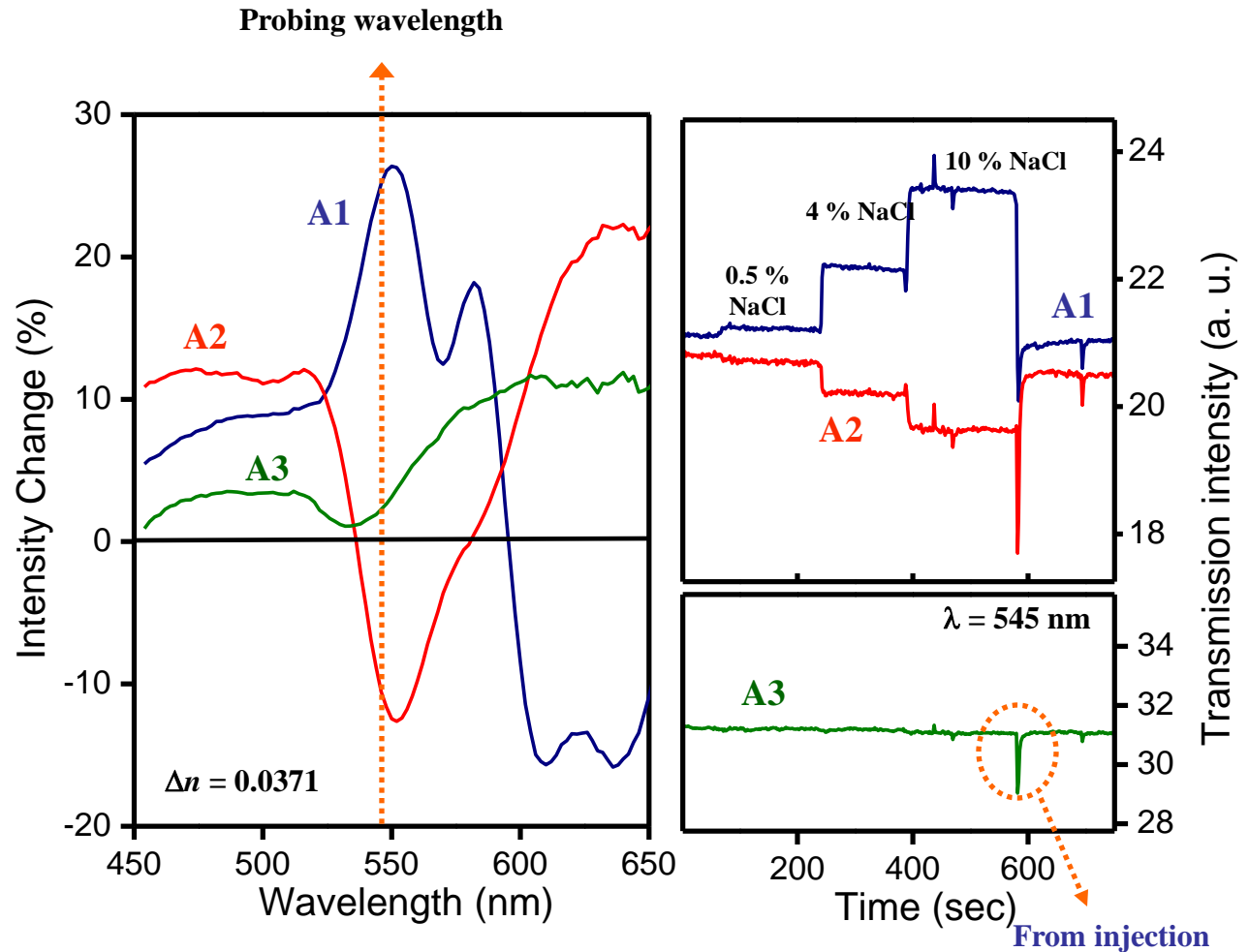
A1



A2



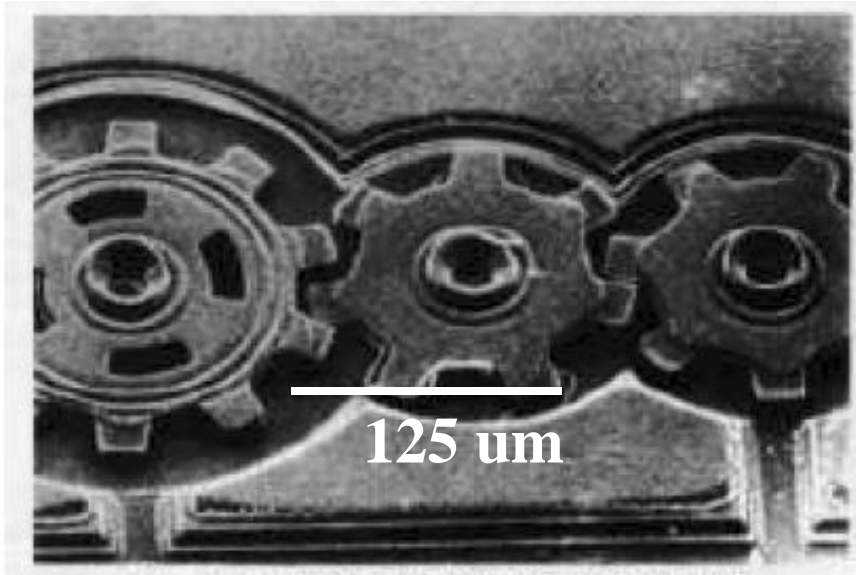
A3



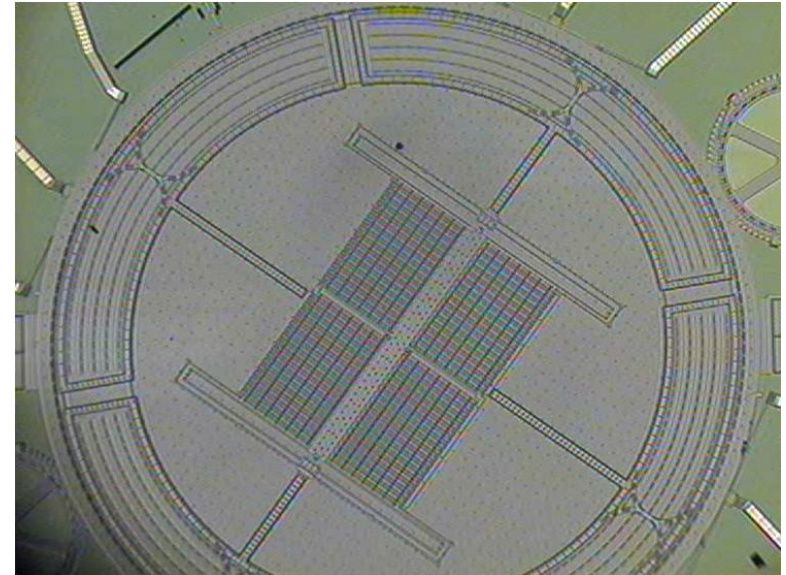


MWNT Integration with MEMS

Micro & Nano Bearings



1988, Bell Labs



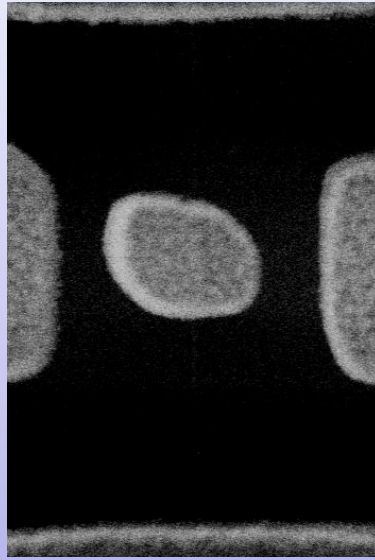
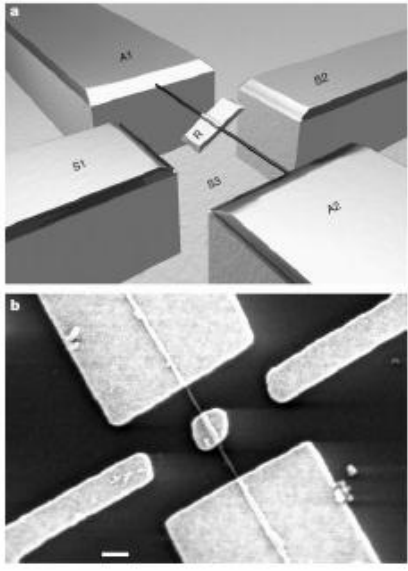
~2006, Sandia

Other approaches: air bearing (MIT), ball bearings (Maryland)...

**Rotational microdevices still only in limited applications
(e.g. Sandia safe and arm)**

WHY? *Reliability, lifetime, complexity, speed, wobble*

Inspiration: Previous Rotating CNT Bearing Devices



A. Zettl, et al., U.C. Berkeley. Retrieved from: <http://www.physics.berkeley.edu/research/zettl/projects/Rotorpics.html>

1. A.M. Fennimore et. al, Nature 424, 408 (2003)

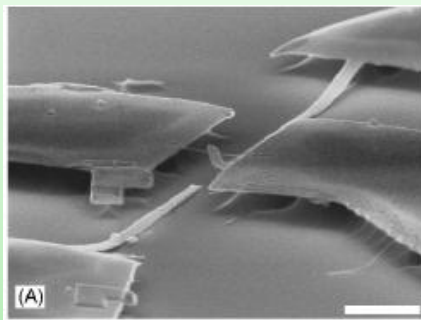
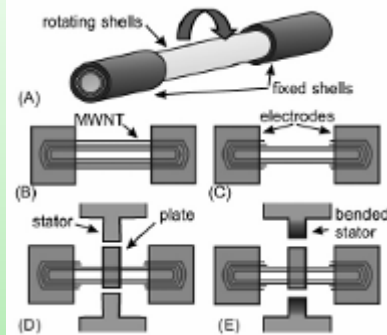
3. John Cumings and A. Zettl, Science 289, 602 (2000).

Two groups have made “see-saw” like flipper devices

(Zettl @ Berkeley, Bournon @ École Normale Supérieure)

Accomplishments:

- Demonstrated CNT rotary bearings
- Demonstrated Electrostatic Motor
- Demonstrated long term, reliable operation
- Noted lack of wear
- One rotary static friction measurement



2. Bertrand Bournon et. al, Nano Letters 4, 709 (2004)

Areas for Improvement:

Used Horizontal Tube → no axisymmetry possible

Axisymmetry would: improve rotor balance
increase speed capability
enable superior electrostatics
enable more complex geometries

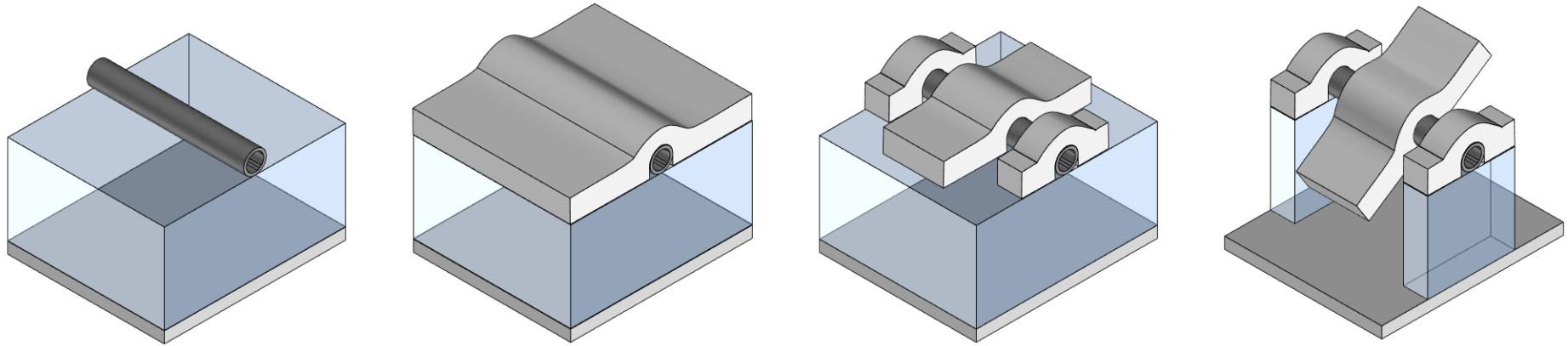
Tubes randomly distributed → no batch fabrication

No dynamic friction measurements

Draper Approach – Vertical Tube Orientation

Enables: axisymmetric design

→ superior rotor balancing, electrodes, turbine blades, etc.

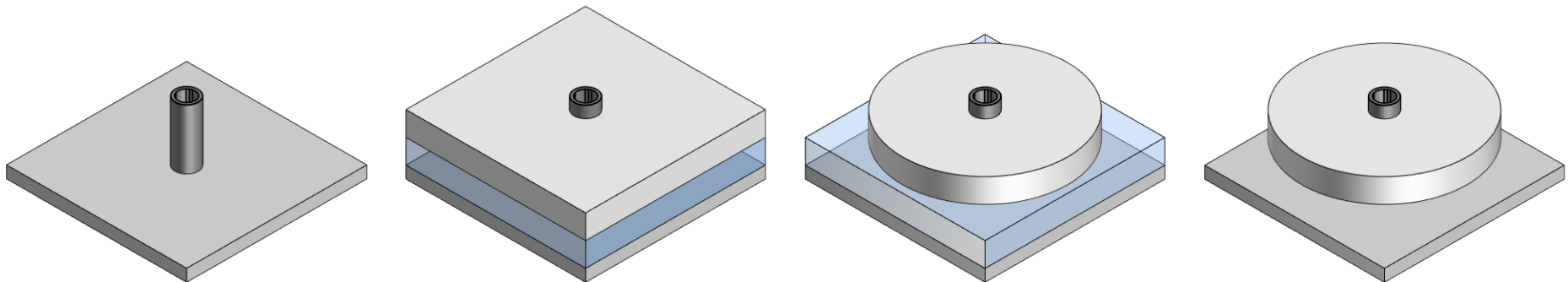


Horizontal Tube
Vertical Tube

Layers
Deposited

Geometry
Defined
Lithographically

See-saw
Axisymmetric Rotor



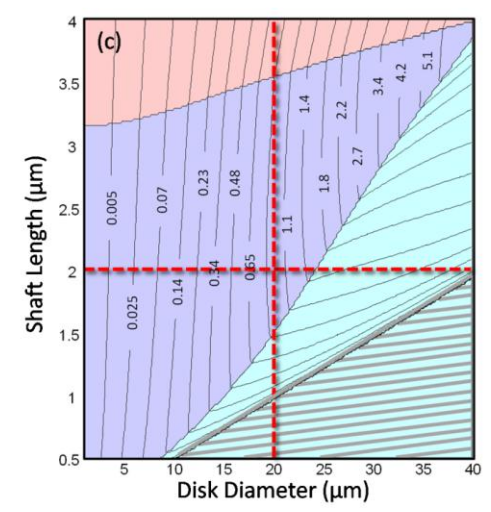
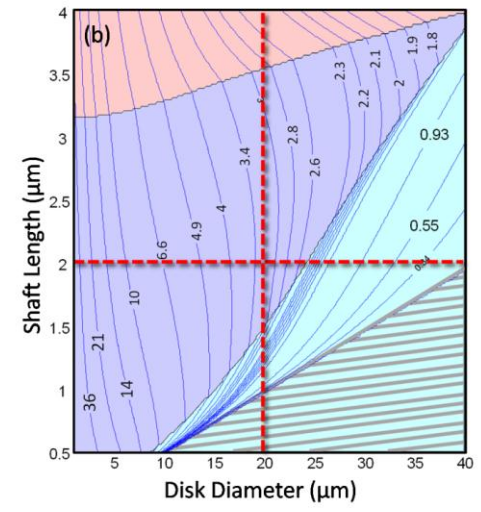
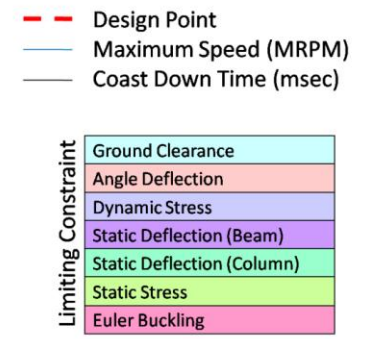
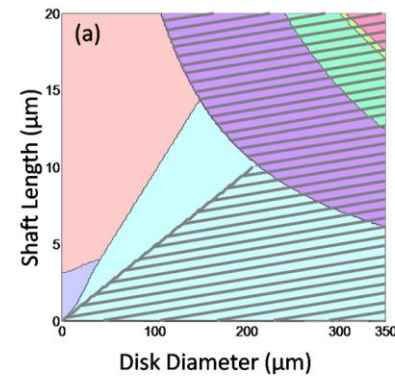
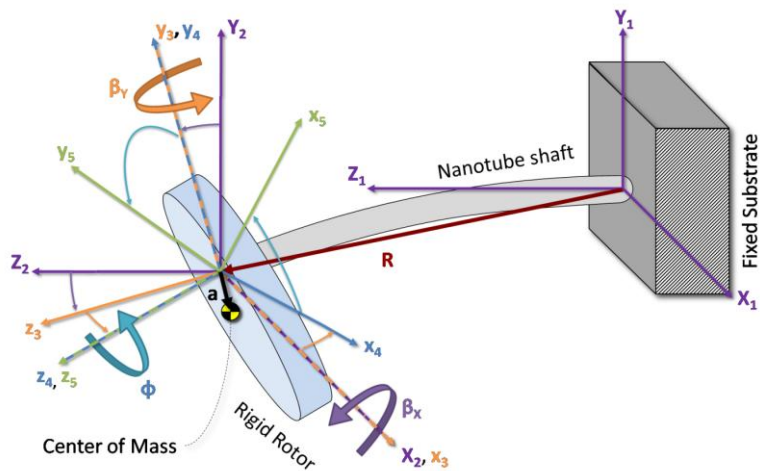
Device Rotordynamic Model

Stodola Rotor – well established dynamics

- 5 degrees of freedom
- Rigid thin disk, Euler simple beam shaft

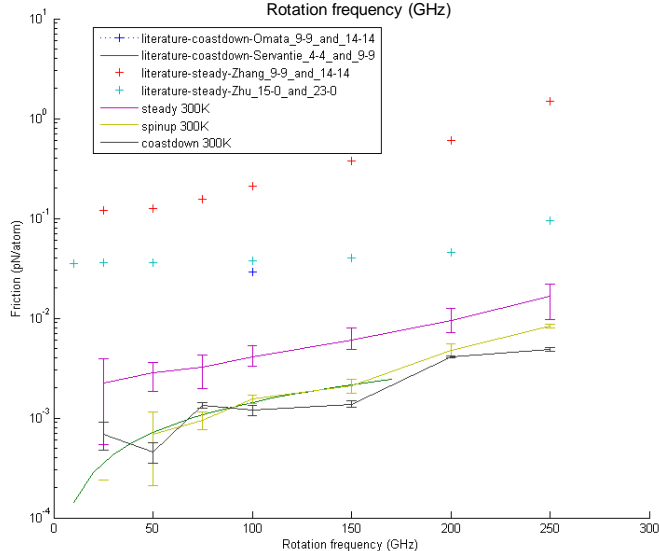
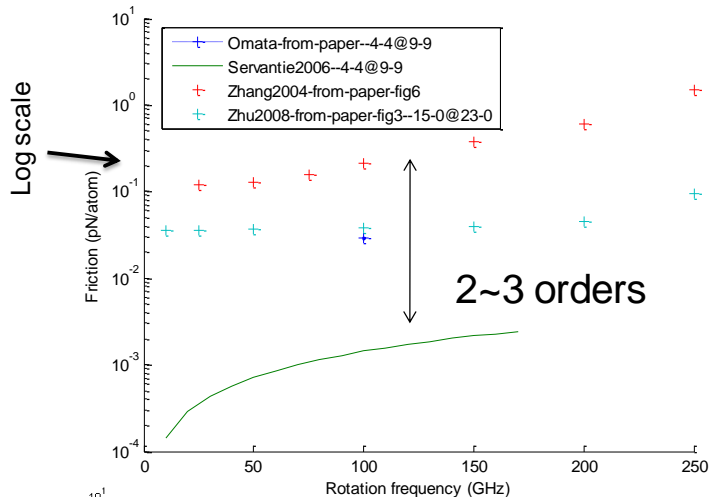
Predicts:

- Natural & critical speeds,
- Angular and lateral displacements induced by imbalance
- Beam stresses

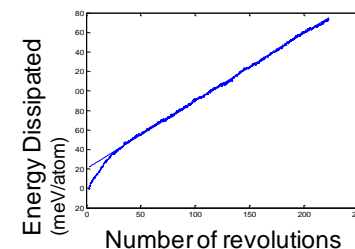
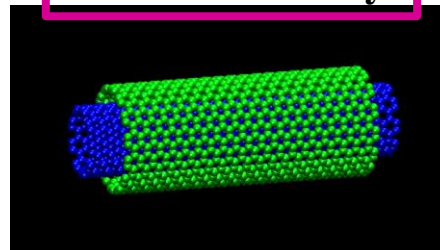


Molecular Dynamics Simulations

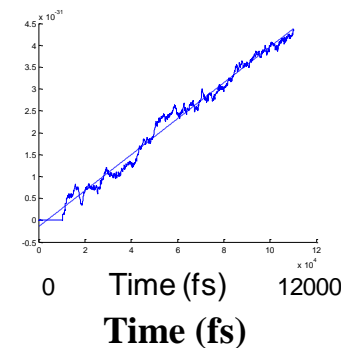
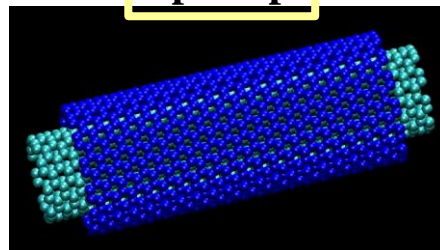
Simulation literature (without suspect papers) gives about 2-3 orders variation in MWNT friction



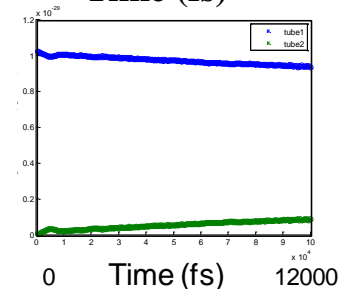
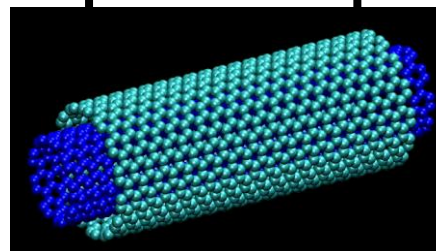
Constant Velocity



Spin-up



Coast-down

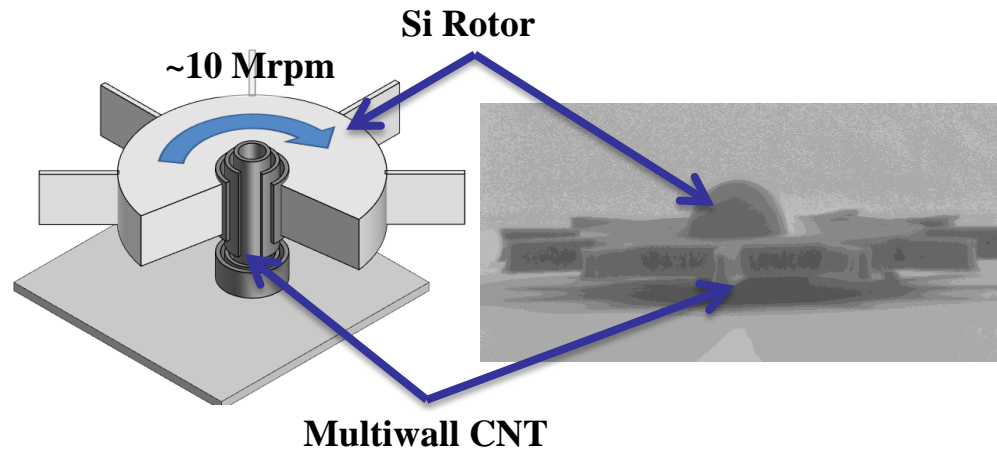


CNT/MEMS Process Compatibility

	Process	Com- patible	SEM	TEM	Notes	Other Refs	Process Parameters	
Deposition	PECVD oxide	yes	X	X	Few or no defects introduced. Conformal, uniform coating. 5-10 nm layer close to tube may have altered composition - not susceptible to HF etch.	2,3	22 sccm SiH ₄ , 750 sccm N ₂ O, 430 sccm N ₂ , 1800 mTorr, 20W, 380° C, 30 sec	
	PECVD nitride	yes	X	X	Few or no defects are introduced by PECVD. Coating is conformal, uniform.	4,5	20 sccm SiH ₄ , 20 sccm NH ₃ , 1000 sccm N ₂ , 650 mTorr, 20 W (7 sec @ kHz, 14 sec @ MHz cycles), 380° C, 2 min	
	LPCVD poly-silicon	yes		X	No defects are introduced by LPCVD. Coating is not uniform (for thin coating); nucleates into poly-crystals.		80 sccm SiH ₄ , 150 mTorr, 585° C, 5 min	
	PECVD amorph-Si	ok		X	Some defects are introduced by PECVD. Coating is conformal, uniform.	6	50 sccm SiH ₄ , 1950 mTorr, 9W, 380° C, 2 min	
Etch	Wet	piranha	yes	X	Very little or no bulk damage to poorly graphitized tubes.		3 H ₂ SO ₄ : 1 H ₂ O ₂ (30%), 30 min, room temperature	
		RCA SC1	ok	X	X	Did not cause much bulk damage. 1-2 outer layers may suffer slight damage. Poorly graphitized tubes showed little or no bulk damage.		5 H ₂ O: 1 NH ₄ OH: 1 H ₂ O ₂ (30%), 30 min, room temperature
		KOH	ok	X	X	Slowly introduces substantial defects at outer walls, but few defects deep within the tube. Poorly graphitized tubes showed small bulk etching.	7,8,9	45% KOH, 80° C, 30 min
		dilute aqua regia	ok	X		Very little or no bulk damage to poorly graphitized tubes. Aqua regia appears to have attacked the catalyst.	10	2 H ₂ O : 1 HNO ₃ (50-70%): 3 HCl (35%), 30 min, room temperature
		isopropanol	yes	X	X	Isopropanol was used for all wet etch runs, which were dried via a critical point dryer. Some of these were compatible, so Isopropanol must also be completely compatible.		30 min (required for critical point drying)
		acetone	yes	X		Very little or no bulk damage to poorly graphitized tubes.	11,12	12 hours, room temperature
		dilute nitric acid	ok	X		Very little or no bulk damage to poorly graphitized tubes. May attack catalyst.	13,14	4 H ₂ O: 1 HNO ₃ (50-70%), 30 min, room temperature
		liquid buffered HF	yes	X	X	BHF does not cause bulk damage to even poorly graphitized tubes. Strips oxide from tube, except for thin layer.	15-17	35% NH ₄ F, 6.25% HF, 58.75% H ₂ O, 30 min, room temperature
	Dry	vapor HF	yes	X		Very little or no bulk damage to poorly graphitized tubes.		40° C, over dish of 49% HF, 30 min
		XeF ₂	yes		X	XeF ₂ causes no damage at all to highly graphitized nanotubes, and little or no visible damage to CVD tubes. It may cause catalyst swelling, or removal of some outer layers of amorphous carbon.		25 cycles of 1 min exposure to XeF ₂ gas
		SF ₆ + O ₂ , RIE (cryo)	ok	X		May strip some outer layers of (probably amorphous) material from poorly graphitized tubes, yielding "match-sticks" with catalyst heads.		50 sccm SF ₆ , 10 sccm O ₂ , 60 mTorr, 100W, 30 min, -25° C
		Ar RIE	no	X		Severe damage or polymerization after long etch. Sharpens tube, causes significant bending.	18	30 sccm Ar, 60 mTorr, 100W, 30 min, room temperature
		SF ₆ RIE	no	X		Severe damage or polymerization after long etch. Sharpens tube, causes significant bending.		60 sccm SF ₆ , 60 mTorr, 100W, 30 min, room temperature
		SF ₆ + O ₂ , RIE	no	X		Severe damage or polymerization after long etch. Sharpens tube, causes significant bending.		60 sccm SF ₆ , 10 sccm O ₂ , 60 mTorr, 100W, 30 min, room temperature
CF ₄ RIE		no	X		Severe damage or polymerization after long etch. Sharpens tube, causes significant bending.		25 sccm CF ₄ , 60 mTorr, 100W, 30 min, room temperature	
CF ₄ + O ₂ , RIE		no	X		Causes etching at the tip, possibly just due to sputtering (as it is uniform across etch chemistries). Sharpens tube.	5	25 sccm CF ₄ , 5 sccm O ₂ , 60 mTorr, 100W, 30 min, room temperature	
DRIE		yes	X		Non-aggressive recipe; little or no bulk damage to poorly graphitized tubes.		Etch cycle: (130 sccm SF ₆ , 13 sccm O ₂ , 20 mTorr, 150W ICP, 22W platen, 8 sec) Passivation cycle: (100 sccm C ₄ F ₈ , 20 mTorr, 600W ICP, 22W platen, 5 sec) Overall: (16 cycles, 2:48 minutes)	
CHF ₃ + CF ₄ RIE		no	X		Causes etching at the tip, possibly just due to sputtering (as it is uniform across etch chemistries). Sharpens tube, causes significant bending.		14.6 sccm CHF ₃ , 1.4 sccm CF ₄ , 20 mTorr, 200W, 30 min, room temperature	
O ₂ plasma RIE					19	30 sccm O ₂ , 60 mTorr, 100W, 30 min, room temperature		
O ₂ plasma ash	no	X	X	Oxygen plasma attacks amorphous carbon strongly, and nanotube walls slowly. Poorly graphitized tubes are strongly damaged. Well graphitized tubes are undamaged.	17	40 sccm O ₂ , 200 mTorr, 55W, 30 min, room temperature		

Status

Device Fabrication Demonstrated

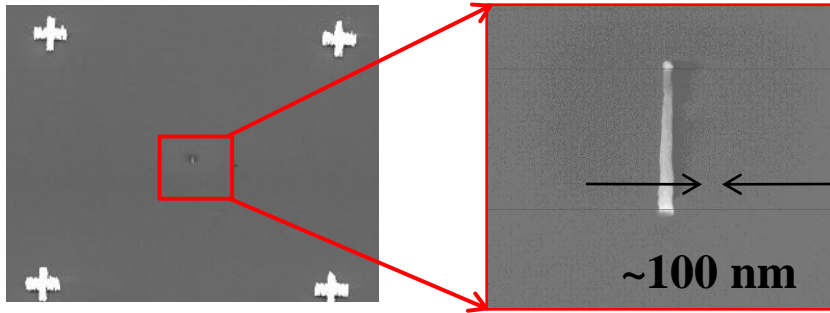


**CVD nanotube quality inadequate for rotation
(also true for COTS nanotubes)**

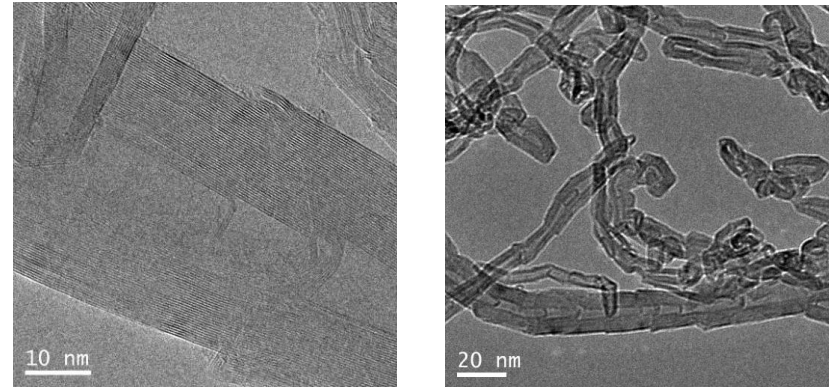
- **Built chamber and optimizing arc-deposition process**
- **Investigating pick-and-place in FIB/nanomanipulator**
- **Possibly electrophoretic placement**

MWNTs

(PE)CVD-grown

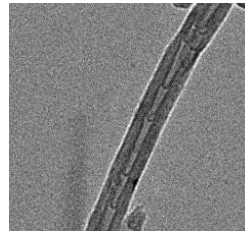
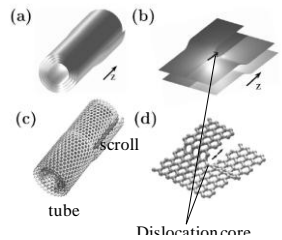


COTS Graphitized MWNTs

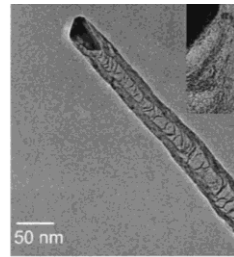


Locally: good crystallinity, no amorphous carbon
Larger-scale: defects (bamboo, kinks, chevrons, etc.)

Issue: Defects

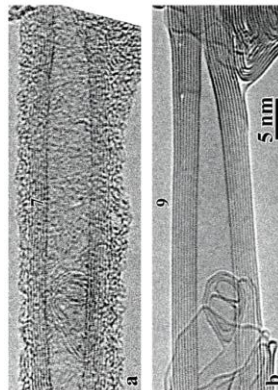
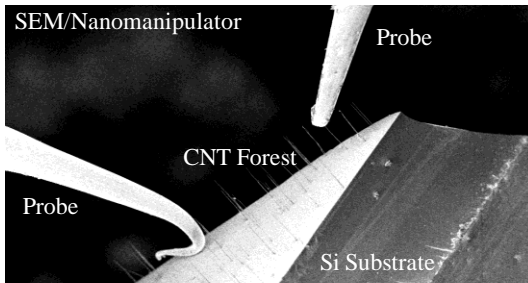


Bamboo Defects

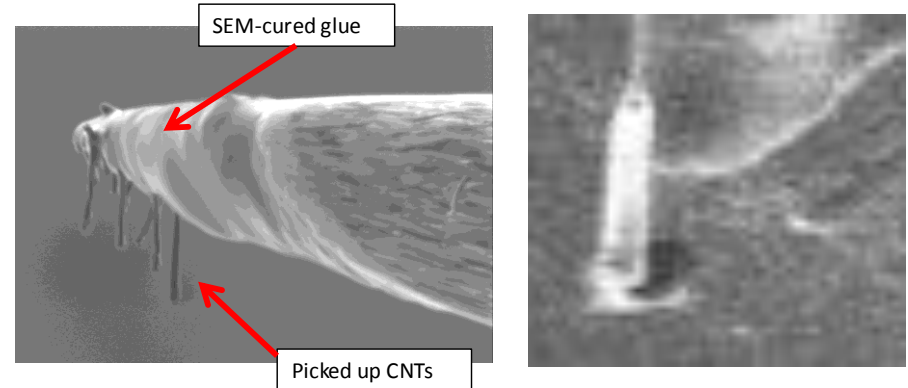


Bowing

Solution: Current Annealing



Arc-Grown CNTs w/ pick-and-place



Thoughts on Challenges and Opportunities for Integrated Nanosystems

- Microfab/top-down nanofab bootstraps from the semiconductor industry
 - *Very good* at planar fabrication
- May not want nanostructures/materials to be planar for best utilization
 - MWNT Bearing offers advantages to going perpendicular to the substrate (~2.5D?)
 - Most surface plasmon structures are 2-D (maybe 2.5D)
 - 3-D could offer optical metamaterials, optical cloaking devices, etc.
 - Biology is not planar; nano-bio interface offers *huge* rewards
 - ***How to fabricate 3D nano/micro structures and interface them with macro structures***
- Best nanostructures may be produced in a messy batch process
 - e.g. Arc-deposited MWNTs
 - ***Techniques to precisely sort/place nanostructures/mat'ls onto/into 2D/3D structures***
- ***Multiscale/multimode simulation*** to fully understand structures and interactions
 - Spanning from molecular interactions potentially to meters
 - e.g. To model gecko: 8 o.o.m. in size (mechanical structures): VdW w/surface, ~100 nm spatulae, ~10100 μm setae, few-mm toes, ~cm paws, ~10 cm body
- ***Fault-tolerant design*** for nano/micro/macrosystems
 - Self-assembly will have defects (thermodynamics)
 - Need electrical, mechanical designs that can deal with those defects
 - Computation, biosensor, gecko adhesive support structure, etc.